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Approved for use through 10/31/2002. OMB 0651-0031

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Substitute for form 1449B/PTO		<b>Compleat if Known</b>	
		<b>Application Number</b>	Not yet assigned
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (use as many sheets as necessary)		<b>Filing Date</b>	August 20, 2003
		<b>First Named Inventor</b>	Walton
		<b>Group Art Unit</b>	Not yet assigned
		<b>Examiner Name</b>	Not yet assigned
		<b>Attorney Docket Number</b>	NC 84,613
Sheet	2	of	2

<b>OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS</b>			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
		MEGER et al, "Bemed-Generated Plasmas for Processing Applications", Amer. Inst. of Physics, May 2001, Vol. 8 No. 5, pp. 2558-2564	
		LEONHARDT et al, "Plasma Diagnostic in Large area Plasma Processing System", Journal of Vacuum Science & Tech., July 2001, Vol. 19 No. 4, pp. 1367-1373	
		WALTON et al, "Ion Energy Distribution in a Pulsed, Electron Beam-Generated Plasma", Journal of Vacuum Science & Tech., July 2001, Vol 19 No. 4, pp. 1325-1329	
		MANHEIMER et al, "Theoretical Overview of the Large-Area Plasma Processing System (LAPPS)", Plasma Sources Science Technology, 2000, Vol 9, pp. 370-386	
		FERNSLER et al, "Production of Large-Area Plasmas by Electron Beams", Amer. Inst. of Physics, May 1998, Vol5 No. 5, pp. 2137-2143	

Examiner Signature		Date Considered	
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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